

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
Chen, et al.

Serial No. 10/712460

Filed: November 13, 2003

For: SEMICONDUCTOR WAFER  
MANUFACTURING METHODS  
EMPLOYING CLEANING DELAY  
PERIOD



§  
§  
§  
§  
§  
§  
§  
§  
§  
§

Attorney Docket No. 24061.42

Customer No. 27683

Group Art Unit: Unknown

Examiner: Unknown

LETTER TO THE OFFICIAL DRAFTSPERSON

Attn: Official Draftsperson  
Commissioner For Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Enclosed are two (2) sheets of formal drawings to replace the informal drawings as originally filed in the above-identified patent application.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "D. O'Dell".

David M. O'Dell  
Reg. No. 42,044

Date: December 11, 2003  
HAYNES AND BOONE, LLP  
901 Main Street, Suite 3100  
Dallas, Texas 75202-3789  
Telephone: 972-739-8638  
Facsimile: 972-692-9101  
File: 24061.42  
R-62041

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to the Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450 on December 11, 2003.

A handwritten signature in black ink, appearing to read "Gayle Conner".  
Gayle Conner